

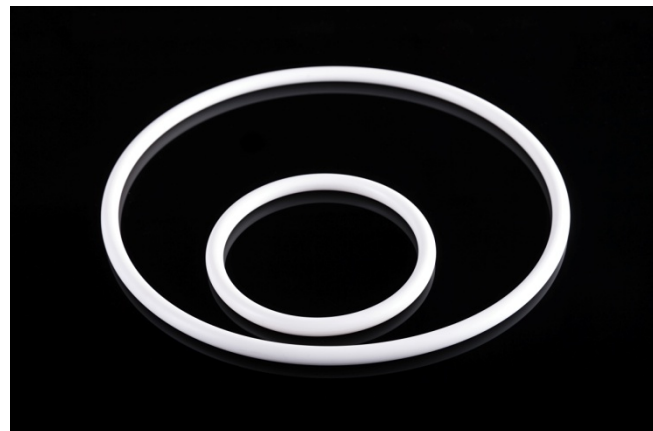
VALQUA Semiconductor Industry Products

SPOQ ARMOR®

High Performance FKM

❖ Product & Benefits

SPOQ ARMOR® is a high performance FKM material recommended for static/dynamic locations. Its plasma resistance properties make the SPOQ ARMOR® suitable for CVD, Etch and Ashing applications.



❖ Featured Benefits

- Plasma Resistance
- Low Adhesion
- Low Metallic Impurities
- Low Outgassing

❖ Applications

- Dry Etch Equipment
- Plasma Enhanced CVD Equipment
- Plasma Ashing Equipment

❖ Contact Us

Valqua America, Inc.
4655 Old Ironsides Dr #380
Santa Clara, CA 95054
www.valqua-america.com

❖ Typical Properties

| Color | White |
|-------------------------------|-------|
| Hardness (Shore A) | 71 |
| Tensile Strength (MPa) | 14.0 |
| Elongation (%) | 240 |
| Modulus 100% Elongation (MPa) | 3.0 |
| Maximum Temperature (°C) | 200 |
| Compression Set (%) | 33 |

*Compression Set: 25% compression at 200°C for 72 hours
Values above are actual measurements, not standards*



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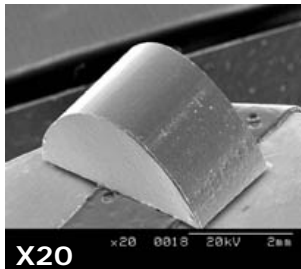
Additional information

SPOQ ARMOR®

❖ Performance Properties

Actual Equipment Evaluation Example

Scanning electron micrograph of elastomer surface after plasma exposure



Equipment: CVD

Location: Slit valve (AS568A-254)

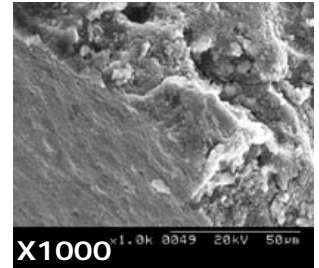
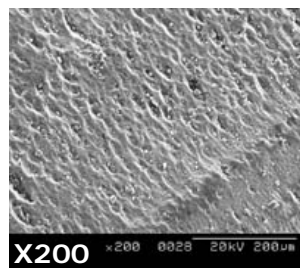
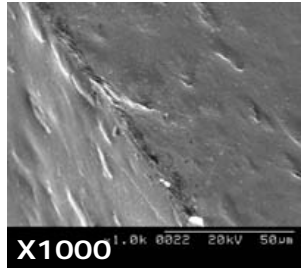
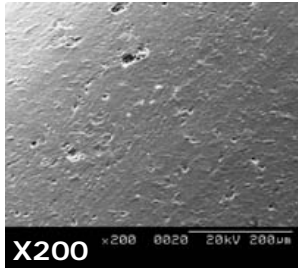
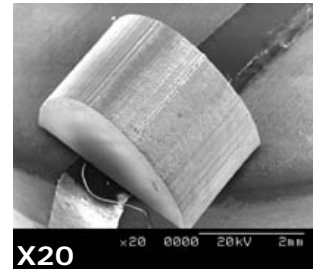
Gas: TEOS+O₂+C₂F₆+TMP

Plasma Power: RF450W

Temperature: 70~80°C

Wafer Count: SPOQ ARMOR 17,000

General FKM 1,700



SPOQ ARMOR

General Fluoro Elastomer